

DRAFTS
BRS, Chen in.

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- (8) ("5872630" or ("6181421" or ("5091320" or ("4653924") PN.
- (12) ("5,608,526" or ("5,867,276" or ("5,963,329" or ("5,973,787" or ("6,031,614" or ("6,2...
- (15) 356/369.cds. and chen in.
- (90848) light adj reflected off same perpendicular and ellipsometer
- (2) light adj reflected adj off same perpendicular and ellipsometer
- (594) 356/369.cds.
- (1) 6486952.LRP.N.
- (1) ("20030107737") PN.
- (0) 20030107737.LRP.N.

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DRAFTS DRAFTS DRAFTS

USPAT:EPG, APO DERWENT, ISM, TDR

Highlight all keywords in body

4,585,348
4,653,924
5,973,787
5,995,226
6,134,011
6,373,871

A B C D E F G H I J K L M N O P Q R S T U V W X Y Z

	U	Document ID	Issue Date	Pages	Title	Current OR	Current XRef	Retrieval Class	Inventor	S	C	P	S	S	S	S	S	S	S
1	<input type="checkbox"/>	US 6373871 B1	20020416	8	Ellipsometer with two lasers	372/28	356/484, 372/29.01,		Hermes, Kees et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	UC
2	<input type="checkbox"/>	US 6134011 A	20001017	10	Optical measurement system using polarized light	356/369	250/225, 356/237.2,		Klein, David L. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	UC
3	<input type="checkbox"/>	US 5995226 A	19991130	7	Optical apparatus for measuring profiles of a wafer	356/511	257/E21.53		Abe, Kohzo et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	UC
4	<input type="checkbox"/>	US 5973787 A	19991026	15	Broadband spectroscopic rotating compensator ellipsometer	356/369	250/225, 356/364		Aspnes, David E. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	UC
5	<input type="checkbox"/>	US 4585348 A	19860429	23	Ultra-fast photometric instrument	356/369			Chastang, Jean-Claude A. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	UC
6	<input type="checkbox"/>	US 4653924 A	19870331	9	Rotating analyzer type ellipsometer	356/369	356/364		Itonaga, Makoto et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	UC
7	<input type="checkbox"/>	JP 11173994 A	20030204	10	Optical measurement system for measuring characteristic of board, thin film				KLEIN, D L et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	UC
8	<input type="checkbox"/>	DE 19826319 A	19981217	7	Optical arrangement for measuring profiles of wafers - has two optical interference				ABE, K et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	UC
9	<input type="checkbox"/>	EP 980519 B	20021010	8	Ellipsometer for analysing samples and reading optical discs - measures intensities				HEMMES, K et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	UC
10	<input type="checkbox"/>	US 5877859 A	20030416		Broadband spectroscopic ellipsometer for evaluating sample - has polychromatic light				ASPINES, D E et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	UC
11	<input type="checkbox"/>	US 4585348 A	19860429		Ultra-fast polarimetric and ellipsometric photometric instrument - drafts only				CHASTANG, J C A et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	UC

Ready

2/24